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SEMICONDUCTOR DEVICE PACKAGE AND A METHOD OF MANUFACTURING THE SAME

Abstract

At least some embodiments of the present disclosure relate to a semiconductor device package. The semiconductor device package includes a first substrate with a first surface and a second surface opposite to the first surface, a second substrate adjacent to the first surface of the first substrate, and an encapsulant encapsulating the first substrate and the second substrate. The first substrate defines a space. The second substrate covers the space. The second surface of the first substrate is exposed by the encapsulant. A surface of the encapsulant is coplanar with the second surface of the first substrate or protrudes beyond the second surface of the first substrate.

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Background/Summary

CROSS-REFERENCE TO RELATED APPLICATION [0001] This application is a continuation of U.S. patent application Ser. No. 18/112,463 filed Feb. 21, 2023, now issued as U.S. Pat. No. 12,283,569, which is a continuation of U.S. patent application Ser. No. 15/960,416 filed Apr. 23, 2018, now issued as U.S. Pat. No. 11,587,903, the contents of which is incorporated herein by reference in its entirety.

BACKGROUND

1. Technical Field

[0002] The present disclosure relates to a semiconductor device package including a first substrate, a second substrate, and an encapsulant.

2. Description of the Related Art

[0003] To improve performance of a semiconductor device package, electronic components or semiconductor devices can be disposed on both sides of a substrate. A frame board, which may surround some components or semiconductor devices, is disposed on the substrate via connection elements (e.g. solder bumps). A multi-side molding technique may be used to encapsulate components or semiconductor devices on both sides of the substrate. Such a multi-side molding technique may involve two molding operations. During the molding operations, the connection elements to connect the frame board to the substrate may be deformed or damaged, which may adversely affect the performance of the semiconductor device package.

SUMMARY

[0004] In some embodiments, according to one aspect, a semiconductor device package includes a first substrate with a first surface and a second surface opposite to the first surface, a second substrate adjacent to the first surface of the first substrate, and an encapsulant encapsulating the first substrate and the second substrate. The first substrate defines a space. The second substrate covers the space. The second surface of the first substrate is exposed by the encapsulant. A surface of the encapsulant is coplanar with the second surface of the first substrate or protrudes beyond the second surface of the first substrate.

[0005] In some embodiments, according to another aspect, a semiconductor device package includes a first substrate with a surface, a second substrate adjacent to the first substrate, an encapsulant encapsulating the second substrate, and a conductive layer disposed on the encapsulant and the surface of the first substrate. The first substrate includes a grounding layer exposed from the surface. The first substrate defines a space. The second substrate covers the space. The encapsulant fills the space. The conductive layer is in contact with the grounding layer. [0006] In some embodiments, according to another aspect, a semiconductor device package includes a first substrate defining a space, a second substrate adjacent to the first substrate and covering the space, a first electronic component, a second electronic component, and an encapsulant. The second substrate has a first surface, a second surface opposite to the first surface and a third surface extending from the first surface to the second surface. The first electronic component is disposed on the first surface of the second substrate. The second electronic

component is disposed on the second surface of the second substrate and in the space of the first substrate. The encapsulant has a surface and encapsulates the first substrate, the second substrate, the first electronic component, and the second electronic component. The third surface of the second substrate is offset from the surface of the encapsulant by a non-zero distance.

[0007] In some embodiments, according to another aspect, a method for manufacturing a semiconductor device package includes: providing a first substrate with a first surface and a second surface opposite to the first surface, the first substrate defining a plurality of spaces; disposing an adhesive layer on the second surface of the first substrate; providing a semiconductor device module on the first surface of the first substrate; and encapsulating the first substrate and the semiconductor device module with an encapsulant.

Description

BRIEF DESCRIPTION OF THE DRAWINGS

[0008] FIG. **1** illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0009] FIG. **2**A illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0010] FIG. **2**B illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0011] FIG. **2**C illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0012] FIG. **3**A illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0013] FIG. **3**B illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0014] FIG. **4**A illustrates a method of manufacturing a semiconductor device package according to some embodiments of the present disclosure.

[0015] FIG. **4**B illustrates a method of manufacturing a semiconductor device package according to some embodiments of the present disclosure.

[0016] FIG. **4**C illustrates a method of manufacturing a semiconductor device package according to some embodiments of the present disclosure.

[0017] FIG. **4**D illustrates a method of manufacturing a semiconductor device package according to some embodiments of the present disclosure.

[0018] FIG. **5** illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0019] FIG. **6**A illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0020] FIG. **6**B illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0021] FIG. 7 illustrates a cross-sectional view of a comparative semiconductor device package.

[0022] FIG. **8**A illustrates a method of manufacturing a comparative semiconductor device package.

[0023] FIG. **8**B illustrates a method of manufacturing a comparative semiconductor device package.

[0024] FIG. **8**C illustrates a method of manufacturing a comparative semiconductor device package.

[0025] FIG. **8**D illustrates a method of manufacturing a comparative semiconductor device package.

DETAILED DESCRIPTION

[0026] Common reference numerals are used throughout the drawings and the detailed description to indicate the same or similar components. Embodiments of the present disclosure will be readily understood from the following detailed description taken in conjunction with the accompanying drawings.

[0027] Spatial descriptions, such as "above," "below," "up," "left," "right," "down," "top," "bottom," "vertical," "horizontal," "side," "higher," "lower," "upper," "over," "under," and so forth, are specified with respect to a certain component or group of components, or a certain plane of a component or group of components, for the orientation of the component(s) as shown in the associated figure. It should be understood that the spatial descriptions used herein are for purposes of illustration only, and that practical implementations of the structures described herein can be spatially arranged in any orientation or manner, provided that the merits of embodiments of this disclosure are not deviated from by such arrangement.

[0028] FIG. **1** is a cross-sectional view of a semiconductor device package **1** in accordance with some embodiments of the present disclosure. The semiconductor device package **1** includes a substrate **10**, a substrate **11**, an encapsulant **12**, a connection element **13**, and electronic components (e.g. semiconductor devices) **14**, **15**, **16**, **17**.

[0029] The substrate **11** has an upper surface **11***u*, an outer/lateral surface **110**, and a lower surface **11***b*. The outer surface **110** of the substrate **11** extends from the upper surface **11***u* to the lower surface **11***b*. In some embodiments, the substrate **11** may include a main board. The electronic components **14** and **15** are disposed on the upper surface **11***u* of the substrate **11**. The electronic components **16** and **17** are disposed on the lower surface **11***b* of the substrate **11**. The electronic components **14**, **15**, **16**, or **17** may constitute at least a portion of a flip chip package, a wire-bond package, or both. The electronic components 14, 15, 16, and 17 may be passive devices (including, for example, a capacitor) and/or active devices (including, for example, a semiconductor die). [0030] The substrate 10 has an upper surface 10u, an outer/lateral surface 100, and a lower surface **10***b*. The outer surface **100** of the substrate **10** extends from the upper surface **10***u* to the lower surface **10***b*. The outer surface **100** of the substrate **10** and the outer surface **110** of the substrate **11** are coplanar. In some embodiments, the substrate **10** may include a frame board. The substrate **10** may include a dielectric layer **101**. The substrate **10** may include a conductive pad surrounded by the dielectric layer **101**. In some embodiments, the dielectric layer **101** may be a solder resist layer. The dielectric layer **101** may be omitted. The substrate **10** is adjacent to the substrate **11**. The substrate **10** is electrically connected to the substrate **11** via the connection element **13**. The connection element **13** may be a solder bump. The substrate **10** defines a space (or an opening) or a plurality of spaces (or a plurality of openings). The electronic components **16** and **17** are disposed at least partially in the space of the substrate **10**. The substrate **11** covers the space. [0031] The encapsulant **12** (which may include a molding compound) has an upper surface **12***u*, an outer/lateral surface **120**, and a lower surface **12b**. The outer surface **120** of the encapsulant **12** may extend from the upper surface **12***u* to the lower surface **12***b* (e.g. may extend around a side of the substrate **11**, not shown). The encapsulant **12** encapsulates the substrate **10** and the substrate **11**. The encapsulant **12** encapsulates the electronic components **14**, **15**, **16**, **17**. The outer surface **100** of the substrate **10**, the outer surface **110** of the substrate **11**, and the outer surface **120** of the encapsulant **12** are coplanar. The lower surface **10**b of the substrate **10** and the lower surface **12**b of the encapsulant 12 are coplanar. The lower surface 10b of the substrate 10 is exposed by the encapsulant **12**. In some embodiments, the encapsulant **12** may completely encapsulate the substrate **11**. In such an embodiment, the outer surface **110** of the substrate **11** may be completely covered by the encapsulant **12**.

[0032] FIG. **2**A is a cross-sectional view of a semiconductor device package **2** in accordance with some embodiments of the present disclosure. The semiconductor device package **2** includes a substrate **10**, a substrate **11**, an encapsulant **22**, a connection element **13**, and electronic components

14, 15, 16, 17.

[0033] The substrate 11 has an upper surface 11u, an outer/lateral surface 110, and a lower surface **11***b*. The outer surface **110** of the substrate **11** extends from the upper surface **11***u* to the lower surface **11***b*. In some embodiments, the substrate **11** includes a main board. The electronic components **14** and **15** are disposed on the upper surface **11***u* of the substrate **11**. The electronic components **16** and **17** are disposed on the lower surface **11***b* of the substrate **11**. [0034] The substrate **10** has an upper surface **10**u, an outer/lateral surface **100**, and a lower surface **10***b*. The outer surface **100** of the substrate **10** extends from the upper surface **10***u* to the lower surface **10***b*. The outer surface **100** of the substrate **10** and the outer surface **110** of the substrate **11** are coplanar. The substrate **10** may include a dielectric layer **101**. The dielectric layer **101** is adjacent to the lower surface **10***b*. The substrate **10** may include a conductive pad surrounded by the dielectric layer **101**. In some embodiments, the dielectric layer **101** may be a solder resist layer. The dielectric layer **101** may be omitted. The substrate **10** is adjacent to the substrate **11**. The substrate **10** is electrically connected to the substrate **11** via the connection element **13**. The substrate **10** defines a space. The electronic components **16** and **17** are disposed in the space of the substrate **10**. The substrate **11** covers the space. The substrate **10** extends horizontally. [0035] The encapsulant 22 has an upper surface 22u, an outer/lateral surface 220, and a lower surface **22***b*. The outer surface **220** of the encapsulant **22** may extend from the upper surface **22***u* to the lower surface **22***b* (e.g. may extend around a side of the substrate **11**, not shown). The encapsulant **22** encapsulates the substrate **10** and the substrate **11**. The encapsulant **22** encapsulates the electronic components 14, 15, 16, 17. The outer surface 100 of the substrate 10, the outer surface **110** of the substrate **11**, and the outer surface **220** of the encapsulant **22** are coplanar. The lower surface **10***b* of the substrate **10** is exposed by the encapsulant **22**. In some embodiments, the encapsulant **22** may completely encapsulate the substrate **11**. In such an embodiment, the outer surface **110** of the substrate **11** may be completely covered by the encapsulant **22**. [0036] The encapsulant **22** includes a portion **221**. The portion **221** protrudes below (or beyond) the substrate **10**. The portion **221** protrudes below the dielectric layer **101** of the substrate **10**. The lower surface **22***b* of the encapsulant **22** is a surface of the portion **221** and protrudes below the surface **10***b* of the substrate **10**. The encapsulant **22** may substantially fill the space defined by the substrate **10**.

[0037] FIG. **2**B is a cross-sectional view of a semiconductor device package **2** including a substrate **10**′ and an encapsulant **22**′ in accordance with some embodiments of the present disclosure, and shows an enlarged view of a region delimited by a dashed line in FIG. **2**A.

[0038] The substrate **10**′ has an upper surface **10**′*u*, an outer/lateral surface **10**′*o*, and a lower surface **10**′*b*. The substrate **10**′ includes a dielectric layer **101**′. The dielectric layer **101**′ may be a solder resist layer. The substrate **10**′ defines a space. Electronic components **16** and **17** are disposed in the space of the substrate **10**′.

[0039] The substrate **10**′ is slightly inclined (e.g. relative to a central portion of the semiconductor device package **2**, and/or relative to a centrally located electronic component, such as the electronic component **17**). A central portion of the substrate **10**′ is higher than a peripheral portion of the substrate **10**′ is closer to the substrate **11** than is a peripheral portion of the substrate **10**′). An inner lateral surface of the substrate **10**′ may be higher than the outer lateral surface **10**′o, The substrate **10**′ is encapsulated by the encapsulant **22**′. The encapsulant **22**′ includes a portion **221**′ having a lower surface **22**′b. The portion **221**′ protrudes below at least a portion of the substrate **10**′. The portion **221**′ protrudes below at least a portion of the substrate **10**′. The lower surface **22**′b of the portion **221**′ protrudes below at least a portion of the surface **10**′b of the substrate **10**′. A central portion of the lower surface **22**′b may protrude further than does an outer portion of the lower surface **22**′b. [0040] FIG. **2**C is a cross-sectional view of the semiconductor device package **2** including a substrate **10**″ and an encapsulant **22**″ in accordance with some embodiments of the present

disclosure, and shows an enlarged view of a region delimited by a dashed line in FIG. **2**A. [0041] The substrate **10**" has an upper surface **10**"*u*, an outer/lateral surface **10**"*o*, and a lower surface **10**"*b*. The substrate **10**" includes a dielectric layer **101**" and a conductive pad **102**". The dielectric layer **101**" may be a solder resist layer. The dielectric layer **101**" surrounds the conductive pad **102**". The substrate **10**" defines a space. Electronic components **16** and **17** are disposed in the space of the substrate **10**".

[0042] The substrate 10" is slightly inclined (e.g. relative to a central portion of the semiconductor device package 2, and/or relative to a centrally located electronic component, such as the electronic component 17). A central portion of the substrate 10" is higher than a peripheral portion of the substrate 10" (e.g. the central portion of the substrate 10" is closer to the substrate 11 than is a peripheral portion of the substrate 10"). An inner lateral surface of the substrate 10" may be higher than the outer lateral surface 10"o, The substrate 10" is encapsulated by the encapsulant 22". The encapsulant 22" includes a portion 221" having a lower surface 22"b. The portion 221" protrudes below at least a portion of the substrate 10". The portion 221" protrudes below at least a portion of the substrate 10". The lower surface 22"b of the portion 221" protrudes below at least a portion of the surface 10"b of the substrate 10". The portion 221" covers a portion of the substrate 10". The portion 221" covers a portion of the substrate 10". The portion 221" partially covers the lower surface 10"b of the substrate 10". The portion 221" and the conductive pad 102" on the substrate 10" are spaced by a distance. In some embodiments (not shown), a central portion of the lower surface 22"b may protrude further than does an outer portion of the lower surface 22"b.

[0043] FIG. **3**A is a cross-sectional view of a semiconductor device package **3** in accordance with some embodiments of the present disclosure. The semiconductor device package **3** includes a substrate **30**, a substrate **11**, an encapsulant **32**, a connection element **13**, electronic components **14**, **15**, **16**, **17**, and a conductive layer **38**.

[0044] The substrate **11** has an upper surface **11***u*, an outer/lateral surface **110**, and a lower surface **11***b*. The outer surface **110** of the substrate **11** extends from the upper surface **11***u* to the lower surface **11***b*. In some embodiments, the substrate **11** may include a main board. The electronic components **14** and **15** are disposed on the upper surface **11***u* of the substrate **11**. The electronic components **16** and **17** are disposed on the lower surface **11***b* of the substrate **11**. [0045] The substrate **30** has an upper surface **30***u*, an outer/lateral surface **300**, and a lower surface

30*b*. The outer surface **300** of the substrate **30** extends from the upper surface **30***u* to the lower surface **30***b*. The outer surface **300** of the substrate **30** and the outer surface **110** of the substrate **11** (which are substantially parallel to one another) are offset from each other, and are not coplanar. In some embodiments, the substrate **30** may include a frame board. The substrate **30** may include a dielectric layer **301**, a conductive pad **302**, and a conductive layer **303**. In some embodiments, the conductive pad **302** may be replaced with a solder bump. The conductive pad **302** is surrounded by the dielectric layer **301** may be omitted. The conductive layer **301** may be a solder resist layer. The dielectric layer **301** may be omitted. The conductive layer **303** may be a grounding layer. The conductive layer **303** is exposed from the outer surface **300**. The substrate **30** is adjacent to the substrate **11**. The substrate **30** is electrically connected to the substrate **11** via the connection element **13**. The substrate **30** defines a space. The electronic components **16** and **17** are disposed in the space of the substrate **30**. The substrate **11** covers the space.

[0046] The encapsulant **32** has an upper surface **32***u*, an outer/lateral surface **320**, and a lower surface **32***b*. The encapsulant **32** encapsulates the substrate **30** and the substrate **11**. The encapsulant **32** encapsulates the electronic components **14**, **15**, **16**, **17**. The outer surface **300** of the substrate **30** and the outer surface **320** of the encapsulant **32** are coplanar. The lower surface **30***b* of the substrate **30** is exposed by the encapsulant **32**. The encapsulant **32** completely encapsulates the substrate **11**. The outer surface **110** of the substrate **11** is completely covered by the encapsulant **32**. The outer surface **110** of the substrate **11** is spaced from the outer surface **320** of the encapsulant **32** by a non-

zero distance. The outer surface **110** of the substrate **11** and the outer surface **320** of the encapsulant **32** (which are substantially parallel to one another) are offset from each other, and are not coplanar. [0047] The encapsulant **32** includes a portion **321**. The portion **321** protrudes below the substrate **30**. The portion **321** protrudes below the dielectric layer **301** of the substrate **30**. The lower surface **32***b* of the portion **321** protrudes below the surface **30***b* of the substrate **30**.

[0048] The conductive layer **38** is disposed on the encapsulant **32** and the outer surface **300** of the substrate **30**. The conductive layer **38** is in contact with the conductive layer **303**. In some embodiments, the conductive layer **38** may be a shielding layer.

[0049] FIG. **3**B is a cross-sectional view of a semiconductor device package **3**′ in accordance with some embodiments of the present disclosure. The semiconductor device package **3**′ includes a substrate **30**′, a substrate **11**, an encapsulant **32**′, a connection element **13**, electronic components **14**, **15**, **16**, **17**, and a conductive layer **38**′.

[0050] The substrate **11** has an upper surface **11**u, an outer/lateral surface **110**, and a lower surface **11**b. The outer surface **110** of the substrate **11** extends from the upper surface **11**u to the lower surface **11**b. In some embodiments, the substrate **11** may include a main board. The electronic components **14** and **15** are disposed on the upper surface **11**u of the substrate **11**. The electronic components **16** and **17** are disposed on the lower surface **11**u of the substrate **11**.

[0051] The substrate **30**′ has an upper surface **30**′*u*, an outer/lateral surface **30**′*o*, and a lower surface **30**′*b*. The outer surface **30**′*o* of the substrate **30**′ and the outer surface **110** of the substrate **11** are coplanar. In some embodiments, the substrate **30** may include a frame board. The substrate **30**′ may include a dielectric layer **301**′, a conductive pad **302**′, and a conductive layer **303**′. The conductive pad **302**′ is surrounded by the dielectric layer **301**′ may be omitted. The conductive layer **301**′ may be a solder resist layer. The dielectric layer **301**′ may be omitted. The conductive layer **303**′ may be a grounding layer. The conductive layer **303**′ is exposed from the outer surface **30**′ o. The substrate **30**′ is adjacent to the substrate **11**. The substrate **30**′ defines a space. The electronic components **16** and **17** are disposed in the space of the substrate **30**′. The substrate **11** covers the space. In some embodiments, the substrate **11** may include a grounding layer exposed from the outer surface **110** of the substrate **11**. The conductive layer **38**′ may contact the grounding layer of the substrate **11** and may be electrically connected to the connection element **13**.

[0052] The encapsulant **32**′ has an upper surface **32**′*u*, an outer/lateral surface **32**′*o*, and a lower surface **32**′*b*. The encapsulant **32**′ encapsulates the substrate **30**′ and the substrate **11**. The encapsulant **32**′ encapsulates the electronic components **14**, **15**, **16**, **17**. The outer surface **30**′ o of the substrate **30**′ and the outer surface **32**′ o of the encapsulant **32**′ are coplanar. The lower surface **30**′ b of the substrate **30**′ is exposed by the encapsulant **32**′.

[0053] The encapsulant **32**′ includes a portion **321**′. The portion **321**′ protrudes below the substrate **30**′. The portion **321**′ protrudes below the dielectric layer **301**′ of the substrate **30**′. The lower surface **32**′*b* of the portion **321**′ protrudes below the surface **30**′*b* of the substrate **30**′.

[0054] The conductive layer **38**′ is disposed on the encapsulant **32**′ and the outer surface **30**′ o of the substrate **30**′. The conductive layer **38**′ is in contact with the conductive layer **30**′. The conductive layer **38**′ is in contact with the outer surface **110** of the substrate **11**. In some embodiments, the conductive layer **38** may be a shielding layer.

[0055] FIG. **4**A through FIG. **4**D illustrate some embodiments of a method of manufacturing the semiconductor device package **1** according to some embodiments of the present disclosure. In some embodiments, a semiconductor device package **2** may be similarly manufactured by the depicted method.

[0056] Referring to FIG. **4**A, a method for manufacturing the semiconductor device package **1** includes providing a substrate **10** with an upper surface **10***u*, an outer/lateral surface **100**, and a lower surface **10***b* opposite to the surface **10***u*. The substrate **10** may include a frame board. The substrate **10** comprises a strip or a panel. The substrate **10** includes a dielectric layer **101**. The

substrate **10** may include a conductive pad surrounded by the dielectric layer **101**. In some embodiments, the dielectric layer **101** may be a solder resist layer. A connection element **13**" is disposed on the upper surface **10**u of the substrate **10**. The connection element **13**" may include a solder material.

[0057] An adhesive layer **100** is disposed on the lower surface **10***b* of the substrate **10**. An individual semiconductor device module **40** is disposed on the upper surface **10***u* of the substrate **10**. The semiconductor device module **40** includes a substrate **11** and electronic components **14**, **15**, **16**, and **17**. The substrate **11** may include a main board. The substrate **11** has an upper surface **11***u*, an outer/lateral surface **110**, and a lower surface **11***b*. Electronic components **14** and **15** are disposed on the upper surface **11***u* of the substrate **11**. Electronic components **16** and **17** are disposed on the lower surface **11***b* of the substrate **11**. A connection element **13**′ is disposed on the semiconductor device module **40**. The connection element **13**′ may include a solder material. [0058] In some embodiments, a strip or a panel of semiconductor device modules **40** is preprocessed by a singulation operation. The strip or a panel of semiconductor device modules **40** is divided into a plurality of units.

[0059] Referring to FIG. **4**B, the semiconductor device module **40** is mounted on the substrate **10**. The semiconductor device module **40** is electrically connected to the substrate **10** via a connection element **13** (e.g. a connection element formed from the connection element **13**").

[0060] Referring to FIG. **4**C, the substrate **10** and the semiconductor device module **40** is encapsulated by a one-time molding operation. The substrate **10** and the semiconductor device module **40** are encapsulated by an encapsulant **12**. During the one-time molding operation, a carrier may be provided on the adhesive layer **100**. The carrier covers the substrate **10**, the adhesive layer **100**, and the semiconductor device module **40**. The carrier may be a mold chase. The one-time molding operation may significantly reduce costs of manufacturing of semiconductor device packages and increase throughputs (e.g. as compared to processes that involve more than a single molding operation).

[0061] Referring to FIG. **4**D, the adhesive layer **100** is removed. Subsequently, a singulation operation is performed. During the singulation operation, the substrate **10** and the encapsulant **12** may be sawed. In some embodiments, the substrate **11** of the semiconductor device module **40** is sawed during the singulation operation.

[0062] FIG. **5** is a cross-sectional view of a semiconductor device package molded in a carrier **500** according to some embodiments of the present disclosure. The carrier **500** is provided on the adhesive layer **100**. The carrier **500** covers the substrate **10**, the adhesive layer **100**, and the semiconductor device module **40**. The carrier **500** may be a mold chase.

[0063] The carrier **500** includes a portion **501** and a portion **502**. The portion **501** presses on the substrate **10**. The portion **502** presses on the adhesive layer **100**. The substrate **10**, the adhesive layer **100**, and the semiconductor device module **40** are disposed between the portion **501** and the portion **502**. The adhesive layer **100** is disposed between the substrate **10** and the portion **502**. The portion **501** may not directly press or contact the semiconductor device module **40**. The portion **501** may not directly press or contact the substrate **11** of the semiconductor device module **40**. The substrate **10** and the semiconductor device module **40** are encapsulated in the carrier **500**. Since the carrier **500** is disposed on the adhesive layer **100**, the carrier **500** may directly press a periphery of the substrate **10** (e.g. on the surface **10***u* of the substrate **10**), and may avoid directly pressing or contacting the substrate **11**. This can help to ensure that the connection element **13** does not deform during the molding operation.

[0064] The semiconductor device package **1** or **2** may be manufactured using the carrier **500**. [0065] FIG. **6**A is a cross-sectional view of a semiconductor device package molded in a carrier **500**' according to some embodiments of the present disclosure. The carrier **500**' is provided on an adhesive layer **100**. The carrier **500**' covers a substrate **10**', the adhesive layer **100**, and a

semiconductor device module **40**. The carrier **500**′ may be a mold chase.

[0066] The carrier **500**′ includes a portion **501** and a portion **502**′. The portion **502**′ includes a protrusion **502**′a (shown in FIG. **6**B). The portion **501** presses on the substrate **10**′. The portion **502**′ presses on the substrate **10**′ (e.g. via the adhesive layer **100**). The substrate **10**′, the adhesive layer **100**, and the semiconductor device module **40** are disposed between the portion **501** and the portion **502**′. The adhesive layer **100** is disposed between the substrate **10**′ and the portion **502**′. A space **503** is defined by two adjacent portions of the portion **502**′. The space **503** is located under the substrate **10**′. The protrusion **502**′a is located under an inner periphery of the substrate **10**′. The protrusion **502**′a correspondingly supports an inner peripheral portion of the substrate **10**′. Since an injecting force of a molding operation may be very large, in some comparative implementations an injected encapsulant may flow or be pushed to a lower surface **10**′b of the substrate **10**′ and may cover the lower surface **10**′b (which may cause a disconnection issue). The design of the carrier **500**′ may help to prevent an encapsulant from flowing or being pushed to the lower surface **10**′b of the substrate **10**′ and covering the lower surface **10**′b.

[0067] FIG. **6**B is a cross-sectional view of a carrier **500**′ according to some embodiments of the present disclosure, and shows an enlarged view of a region delimited by a dashed line in FIG. **6**A. The protrusion **502**′*a* of the carrier **500**′ supports an inner peripheral portion of the substrate **10**′, and may not fully support a central portion of the substrate **10**′. Accordingly, the substrate **10**′ may slightly deform during the molding operation. The substrate **10**′ may be slightly inclined. A central portion of the substrate **10**′ may be higher than a peripheral portion of the substrate **10**′. [0068] A surface **502**′*u* of the portion **502**′ and a lower surface of the adhesive layer **100** are spaced by a distance **D1**. The distance **D1** is in a range from approximately 0.01 millimeters (mm) to approximately 0.02 mm. An outer surface of the protrusion **502**′*a* and an inner surface of the substrate **10**′ are offset by a distance **D2**. The distance **D2** is in a range from approximately 0.2 mm to approximately 0.25 mm.

[0069] According to the design of the carrier **500**′, the substrates **10**′ and **10**″ of FIG. **2**B and FIG. **2**C may be manufactured.

[0070] FIG. **7** is a cross-sectional view of a comparative semiconductor device package **6**. The semiconductor device package **6** includes a substrate **60**, a substrate **61**, an encapsulant **62**, a connection element **63**, and electronic components **14**, **15**, **16**, **17**.

[0071] The substrate **61** has an upper surface **61***u*, an outer/lateral surface **610**, and a lower surface **61***b*. The substrate **11** includes a main board. The electronic components **14** and **15** are disposed on the upper surface **61***u* of the substrate **61**. The electronic components **16** and **17** are disposed on the lower surface **61***b* of the substrate **61**.

[0072] The substrate **60** has an upper surface **60***u*, an outer/lateral surface **600**, and a lower surface **60***b*. The substrate **60** may include a frame board. The substrate **60** may include a solder resist layer and a conductive pad. The conductive pad is surrounded by the solder resist layer. The substrate **60** is adjacent to the substrate **61**. The substrate **60** is electrically connected to the substrate **61** via the connection element **63**. The connection element **63** is a solder bump. The substrate **60** defines a space. The electronic components **16** and **17** are disposed in the space of the substrate **60**. The substrate **61** covers the space.

[0073] The encapsulant **62** has an upper surface **62***u*, an outer/lateral surface **620**, and a lower surface **62***b*. The encapsulant includes a portion **621** and a portion **622**. The encapsulant **62** encapsulates the substrate **60** and the substrate **61**. The encapsulant **12** encapsulates the electronic components **14**, **15**, **16**, **17**. The lower surface **60***b* of the substrate **10** is lower than the lower surface **62***b* of the encapsulant **62**. The lower surface **60***b* of the substrate **60** is exposed by the encapsulant **62**. Part of an inner peripheral surface of the substrate **60** is exposed by the encapsulant **62**.

[0074] FIG. 8A through FIG. 8D illustrate some embodiments of a method of manufacturing the

semiconductor device package 6.

[0075] Referring to FIG. **8**A, a method for manufacturing the semiconductor device package **6** includes providing a substrate **61** with an upper surface **61***u*, an outer/lateral surface **610**, and a lower surface **61***b* opposite to the surface **61***u*. The substrate **61** comprises a strip or a panel. A substrate **60** is provided on the substrate **61**. The substrate **60** has an upper surface **60***u*, an outer/lateral surface **600**, and a lower surface **60***b* opposite to the surface **60***u*. The substrate **60** is mounted on the lower surface **61***b* of the substrate **61** via the connection element **63**. The substrate **60** comprises a strip or a panel. Electronic components **16** and **17** are disposed on the lower surface **61***b* of the substrate **61**.

[0076] Referring to FIG. **8**B, an adhesive layer **600** is provided on the substrate **60** and subsequently, a first molding operation is performed. During the first molding operation, a mold chase may directly press the substrate **61** and the adhesive layer **600**. The substrate **60**, the substrate **61**, and the electronic components **16** and **17** are encapsulated by an encapsulant **621**. Since the mold chase would directly press the substrate **61** and the adhesive layer **600** during the first molding operation, the lower surface **60***b* of the substrate **60** and a lower surface of encapsulant **621** are not coplanar.

[0077] Furthermore, since the substrate **61** is pressed by the mold chase, the connection element **63** may deform by the pressure from the mold chase. The deformation of the connection element **63** may cause a delamination between the connection element **63** and the encapsulant **621**. [0078] Referring to FIG. **8**C, electronic components **14** and **15** are disposed on the upper surface **61**u of the substrate **61**. The adhesive layer **600** is removed.

[0079] Referring to FIG. **8**D, a second molding operation is performed. The substrate **61** and the electronic components **14** and **15** are encapsulated by an encapsulant **622**. An encapsulant **62** including the encapsulant **621** and the encapsulant **622** encapsulates the substrate **60**, the substrate **61**, and the electronic components **14**, **15**, **16**, and **17**. Subsequently, a singulation operation is performed. The lower surface **60***b* of the substrate **10** is higher than a lower surface of the encapsulant **62**.

[0080] As used herein and not otherwise defined, the terms "substantially," "substantial," "approximately" and "about" are used to describe and account for small variations. When used in conjunction with an event or circumstance, the terms can encompass instances in which the event or circumstance occurs precisely as well as instances in which the event or circumstance occurs to a close approximation. For example, when used in conjunction with a numerical value, the terms can encompass a range of variation of less than or equal to $\pm 10\%$ of that numerical value, such as less than or equal to $\pm 5\%$, less than or equal to $\pm 4\%$, less than or equal to $\pm 3\%$, less than or equal to $\pm 2\%$, less than or equal to $\pm 1\%$, less than or equal to $\pm 0.5\%$, less than or equal to $\pm 0.1\%$, or less than or equal to $\pm 0.05\%$. The term "substantially coplanar" can refer to two surfaces within micrometers of lying along a same plane, such as within 40 μm, within 30 μm, within 20 μm, within 10 μm, or within 1 μm of lying along the same plane. For example, "substantially parallel" can refer to a range of angular variation relative to 0° that is less than or equal to $\pm 10^{\circ}$, such as less than or equal to $\pm 5^{\circ}$, less than or equal to $\pm 4^{\circ}$, less than or equal to $\pm 2^{\circ}$, less than or equal to $\pm 1^{\circ}$, less than or equal to $\pm 0.5^{\circ}$, less than or equal to $\pm 0.1^{\circ}$, or less than or equal to $\pm 0.05^{\circ}$. For example, "substantially perpendicular" can refer to a range of angular variation relative to 90° that is less than or equal to $\pm 10^{\circ}$, such as less than or equal to $\pm 5^{\circ}$, less than or equal to $\pm 4^{\circ}$, less than or equal to $\pm 3^{\circ}$, less than or equal to $\pm 2^{\circ}$, less than or equal to $\pm 1^{\circ}$, less than or equal to $\pm 0.5^{\circ}$, less than or equal to $\pm 0.1^{\circ}$, or less than or equal to $\pm 0.05^{\circ}$. [0081] As used herein, the singular terms "a," "an," and "the" may include plural referents unless the context clearly dictates otherwise. In the description of some embodiments, a component provided "on" or "over" another component can encompass cases where the former component is

directly on (e.g., in physical contact with) the latter component, as well as cases where one or more

intervening components are located between the former component and the latter component.

[0082] As used herein, the terms "conductive," "electrically conductive" and "electrical conductivity" refer to an ability to transport an electric current. Electrically conductive materials typically indicate those materials that exhibit little or no opposition to the flow of an electric current. One measure of electrical conductivity is Siemens per meter (S/m). Typically, an electrically conductive material is one having a conductivity greater than approximately 10.sup.4 S/m, such as at least 10.sup.5 S/m or at least 10.sup.6 S/m. The electrical conductivity of a material can sometimes vary with temperature. Unless otherwise specified, the electrical conductivity of a material is measured at room temperature.

[0083] While the present disclosure has been described and illustrated with reference to specific embodiments thereof, these descriptions and illustrations are not limiting. It should be understood by those skilled in the art that various changes may be made and equivalents may be substituted without departing from the true spirit and scope of the present disclosure as defined by the appended claims. The illustrations may not necessarily be drawn to scale. There may be distinctions between the artistic renditions in the present disclosure and the actual apparatus due to manufacturing processes and tolerances. There may be other embodiments of the present disclosure which are not specifically illustrated. The specification and the drawings are to be regarded as illustrative rather than restrictive. Modifications may be made to adapt a particular situation, material, composition of matter, method, or process to the objective, spirit and scope of the present disclosure. All such modifications are intended to be within the scope of the claims appended hereto. While the methods disclosed herein have been described with reference to particular operations performed in a particular order, it will be understood that these operations may be combined, sub-divided, or re-ordered to form an equivalent method without departing from the teachings of the present disclosure. Accordingly, unless specifically indicated herein, the order and grouping of the operations are not limitations.

Claims

- 1. A semiconductor device package, comprising: a first substrate having a first surface and a second surface opposite to the first surface; a second substrate disposed over the first surface of the first substrate; and an encapsulant covering the first surface and the second surface of the first substrate, wherein a portion of the second surface of the first substrate is exposed from the encapsulant, wherein the first substrate has a first lateral surface substantially aligned with a lateral surface of the second substrate.
- **2.** The semiconductor device package of claim 1, further comprising a plurality of conductive elements disposed between the first substrate and the second substrate and electrically connecting the first substrate with the second substrate.
- **3.** The semiconductor device package of claim 2, wherein a first portion of the encapsulant encapsulates the plurality of conductive elements.
- **4.** The semiconductor device package of claim 3, wherein the first portion of the encapsulant includes a first part disposed between adjacent two of the plurality of conductive elements.
- **5.** The semiconductor device package of claim 4, wherein the first part of the first portion of the encapsulant includes a first curved lateral surface and a second curved lateral surface opposite to the first curved lateral surface.
- **6.** The semiconductor device package of claim 5, wherein the first curved lateral surface and the second curved lateral surface are concave toward each other.
- 7. The semiconductor device package of claim 2, further comprising a plurality of conductive pads disposed adjacent to the second surface of the first substrate, wherein one of the plurality of conductive elements overlaps a respective one of the plurality of conductive pads along a direction substantially perpendicular to the second surface of the first substrate.
- **8.** The semiconductor device package of claim 2, further comprising an electronic component

disposed over the second substrate, and vertically overlapping adjacent two of the plurality of conductive elements in the cross-sectional view.

- **9.** A semiconductor device package, comprising: a first substrate having a first surface and a second surface opposite to the first surface; a second substrate disposed over the first surface of the first substrate; an encapsulant covering the first surface and the second surface of the first substrate, wherein the encapsulant has a slanted surface; and a solder resist layer disposed under the second surface of the first substrate, wherein the slanted surface of the encapsulant connects to a bottom surface of the solder resist layer.
- **10**. The semiconductor device package of claim 9, further comprising a conductive bump disposed adjacent to the second surface of the first substrate, and surrounded by the solder resist layer.
- **11**. The semiconductor device package of claim 10, wherein the conductive bump contacts the solder resist layer, wherein the conductive bump does not contact the encapsulant.
- **12**. The semiconductor device package of claim 10, wherein an elevation of a bottommost point of the conductive bump is lower than an elevation of a bottommost point of the slanted surface of the encapsulant.
- **13.** The semiconductor device package of claim 9, further comprising a conductive bump disposed adjacent to the second surface of the first substrate, wherein the solder resist layer has a lateral surface facing the conductive bump, wherein the lateral surface the solder resist layer is closer to the conductive bump than the slanted surface of the encapsulant is.
- **14**. The semiconductor device package of claim 9, wherein a first portion of the encapsulant is disposed under the second surface of the first substrate and has the slanted surface, wherein the first portion of the encapsulant tapers away from the first substrate.
- **15**. The semiconductor device package of claim 14, further comprising an electronic component disposed over the second substrate, wherein a lateral surface of the electronic component vertically overlaps the first portion of the encapsulant.
- **16.** A semiconductor device package, comprising: a first substrate having a first surface, a second surface opposite to the first surface and a first lateral surface extending between the first surface and the second surface; a second substrate disposed over the first substrate; and an encapsulant continuously covering the first surface, the first lateral surface and the second surface of the first substrate in a cross-sectional view.
- **17**. The semiconductor device package of claim 16, wherein the encapsulant includes a first portion covering the first surface of the first substrate and a second portion covering the second surface of the first substrate, wherein a vertical thickness of the first portion of the encapsulant is greater than a vertical thickness of the second portion of the encapsulant.
- **18**. The semiconductor device package of claim 16, wherein the second portion of the encapsulant partially covers a solder resist layer disposed on the second surface of the first substrate.
- **19**. The semiconductor device package of claim 18, wherein the solder resist layer surrounds a conductive bump disposed on the second surface of the first substrate, wherein the first portion of the encapsulant surrounds a conductive element disposed on the first surface of the first substrate, wherein a maximum thickness of the conductive bump is less than a maximum thickness of the conductive element.
- **20**. The semiconductor device package of claim 16, wherein the first substrate further has a second lateral surface extending between the first surface and the second surface, wherein the encapsulant further continuously covers the first surface, the second lateral surface and the second surface of the first substrate in the cross-sectional view.